

12/11/03

Sheet 1 of 5

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. M122-2463		PRIORITY SERIAL NO. <u>09/095,333</u>	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT John T. Moore et al.			
					PRIORITY FILING DATE November 26, 2001		PRIORITY GROUP 2815	

10/734419

U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
MEW	AA	5,219,788	6/93	Abernathy et al.			
	AB	5,045,847	9/91	Tarui et al.			
	AC	5,045,345	9/91	Singer			
	AD	4,996,081	2/91	Elul et al.			
	AE	3,884,698	5/75	Kakihama et al.			
	AF	5,518,946	5/96	Kuroda			
	AG	5,489,542	2/96	Iwai et al.			
	AH	4,330,569	5/82	Gulett et al.			
	AI	4,499,656	2/85	Fabian et al.			
	AJ	5,554,418	9/96	Ito et al.			
	AK	5,926,739	7/99	Rolfson et al.			

FOREIGN PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
MEW	AL	401086562	3/89	Japan			
	AM	362137854	6/87	Japan			
	AN	2129217	5/84	Great Britain			
	AO	2170649	8/86	Great Britain			
	AP	2145243	3/85	Great Britain			
	AQ	403075158	3/91	Japan			

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
MEW	AR		Silicon Proc. for VLSI; 177-178; Vol. 1; S. Wolf
MEW	AS		Silicon Proc. for VLSI; 191-193; Vol. 1; S. Wolf

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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2463	PRIORITY SERIAL NO. 09/995,343 10/734419
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT John T. Moore et al.	
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U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
<i>Mew</i>	AA	4,874,716	10/89	Rao			
	AB	5,587,344	12/96	Ishikawa			
	AC	4,439,270	3/84	Powell et al.			
	AD	5,773,325	6/98	Teramoto			
	AE	5,904,523	5/99	Feldman et al.			
	AF	5,891,793	4/99	Gardner et al.			
	AG	5,795,821	8/98	Bacchetta et al.			
	AH	5,918,147	6/99	Filipiak et al.			
	AI	5,882,978	3/99	Srinivasan et al.			
	AJ	4,612,629	9/86	Harari			
	↓	AK	5,831,321	11/98	Nageyama		

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					Yes	No	
AL							
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AO							
AP							
AQ							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
<i>Mew</i>	AR	Silicon Proc. for VLSI; 37-38; 598-599; Vol. 2; S. Wolf	
<i>Mew</i>	AS	Electronic Materials Science: For Integrated Circuits; 1990 ©; Mayer et al; pp. 269-274; Pub. 1990	

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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2463		PRIORITY SERIAL NO. 09993,312	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT John T. Moore et al.		10/734419	
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U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
NEW	AA	3,549,411	12/70	Bean			
	AB	4,446,194	5/84	Candelaria			
	AC	4,485,553	12/84	Christian			
	AD	4,543,707	10/85	Ito et al.			
	AE	5,098,865	3/92	Machado et al.			
	AF	5,160,998	11/92	Itoh et al.			
	AG	5,306,946	4/94	Yamamoto			
	AH	5,442,223	8/95	Fujii			
	AI	5,523,616	6/96	Den			
	AJ	5,756,404	5/98	Friedenreich et al.			
	AK	5,834,374	11/98	Cabral Jr. et al.			

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					Yes	No	
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
NEW	AR		Intrinsic Stress in Silicon Nitride and Silicon Dioxide Films Prepared by Various Deposition Techniques; 1988 IEEE Internat. Sympos. On Electrical Insulation, Boston, MA; June 5-8, 1988; 1 page; Kanicki, J. et al.
NEW	AS		Passivation of GaAsFET's with PECVD Silicon Nitride Films of Different Stress States; IEEE Transactions on Electron Devices; Vol. 35, No. 9; Sept. 1988; pp. 1412-1418

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LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT John T. Moore et al.		10/734419
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U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
MEW	AA	4,695,872	9/87	Chatterjee			
	AB	5,178,016	1/93	Dauenhauer et al.			
	AC	5,985,771	11/99	Moore et al.			
	AD	3,649,884	3/72	Haneta			
	AE	4,868,632	9/89	Hayashi			
	AF	5,304,829	4/94	Mori et al.			
	AG	5,925,494	7/99	Horn			
	AH	4,075,367	2/78	Gullett			
	AI	4,732,858	3/88	Brewer et al.			
	AJ	6,300,253	10/01	Moore, John T.			
V	AK	4,698,787	10/87	Mukherjee et al.			

FOREIGN PATENT DOCUMENTS							
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MEW	AR	Silicon Nitride Overcoats for Thin Film Magnetic Recording Media; IEEE Transactions on Magnetics; Vol 27. No. 6, Nov. 1991; pp. 5070-5072	
	AS		

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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2463		PRIORITY SERIAL NO. 093995392 101734419	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT John T. Moore et al.		PRIORITY GROUP 2815	
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U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
NEW	AA	4,939,559	07/90	DiMaria et al.			
	AB	6,140,181	10/00	Forbes et al.			
	AC	6,143,627	11/00	Robinson			
	AD	5,877,069	03/99	Robinson			
	AE	6,093,956	07/00	Moore et al.			
	AF	6,103,619	08/00	Lai			
	AG	6,265,241	07/01	Pan			
	AH	6,420,777		Lam et al.			
	AI	6,417,559	07/02	Moore et al.			
	AJ	5,041,888	08/91	Possin et al.			
	AK	6,143,662	11/00	Rhodes et al.			
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